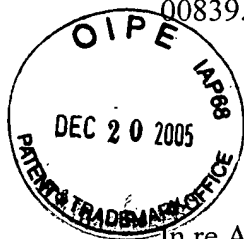


IFW

00839.000419.1

PATENT APPLICATION



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
	:	Examiner: Maureen G. Arancibia
MAKOTO HIGASHIKAWA ET AL.)	
	:	Group Art Unit: 1763
Application No.: 10/656,130)	
	:	
Filed: September 8, 2003)	
	:	
For: PROCESS FOR FORMING A)	
MICROCRYSTALLINE	:	
SILICON SERIES THIN)	
FILM AND APPARATUS	:	
SUITABLE FOR PRACTICING)	
SAID PROCESS	:	December 19, 2005

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Sir:

(a) Introductory Comments

In response to the Office Action dated September 20, 2005, kindly amend
the subject application as follows: